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IN THE UNITED STATES PATENT AND TRIADEMARK OFFICE

In re Application of

Cabral et al.

Serial No.: 09/902,483

Group Art Unit: 2813

Filed: July 11, 2001

Examiner: Erik Kielin

For:

SELF-ALIGNED SILICIDE (SALICIDE) PROCESS FOR LOW RESISTIVITY

CONTACTS TO THIN FILM SILICON-ON-INSULATOR AND BULK MOSFETS

AND FOR SHALLOW JUNCTIONS

Honorable Commissioner of Patents Alexandria, VA 22313-1450

RESPONSE UNDER 37 C.F.R. §1.111

Sir:

In response to the Office Action dated May 25, 2004, please amend the above- identified application as follows:

INTRODUCTORY COMMENTS

There are no amendments to the Claims. However, for the Examiner's convenience, attached is a listing of the pending claims which begins on page 2 of this paper. Remarks begin on page 10 of this paper.